

LIST OF DOCUMENTS CITED BY APPLICANT

Atty. Docket No.

Appln. No.

A-9183

10/069,768

Applicant

Tarak A. RAILKAR et al.

Filing Date

Group

July 1, 2002

2881

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
OK	AA	6,008,525	12/28/99	Barron et al.	257	629	
OK	AB	5,352,330	10/04/94	Wallace	156	643	
OK	AC	5,665,637	09/09/97	Chand	372	46	
OK	AD	4,406,053	09/27/83	Takasaki et al.	29	588	
OK	AE	5,139,606	08/18/92	Maki	156	643	
OK	AF	5,736,709	04/07/98	Neiheisel	219	121.61	
	AG						
	AH						
	AI						
	AJ						

FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
OK	AK	63-102918	05/07/88	Japan			Abstract
	AL						
	AM						

OTHER (including author, title, date, pertinent pages, etc.)

OK	AN	N.C. Tien et al., "Surface adhesion reduction in silicon microstructures using femtosecond laser pulses", <u>Appl. Phys. Lett.</u> , 68 (2), 8 January 1996, pp. 197-199.					
	AO						
	AP						

Examiner

Date Considered

Christy Hawacek

1/7/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.